

1/10

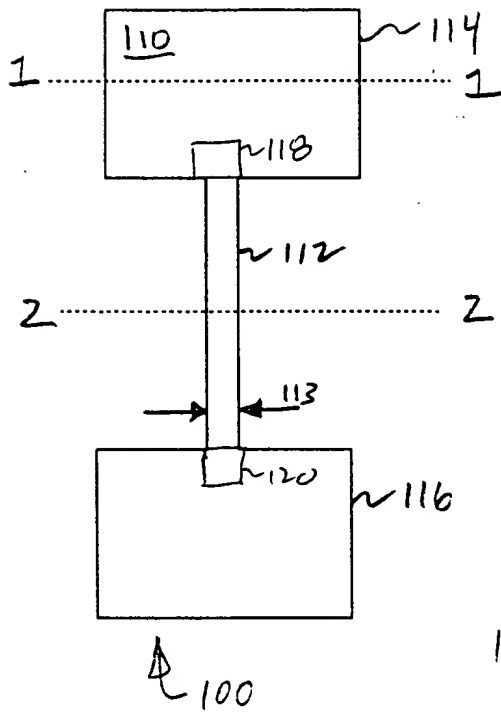
[illegible]

FIG. 1A

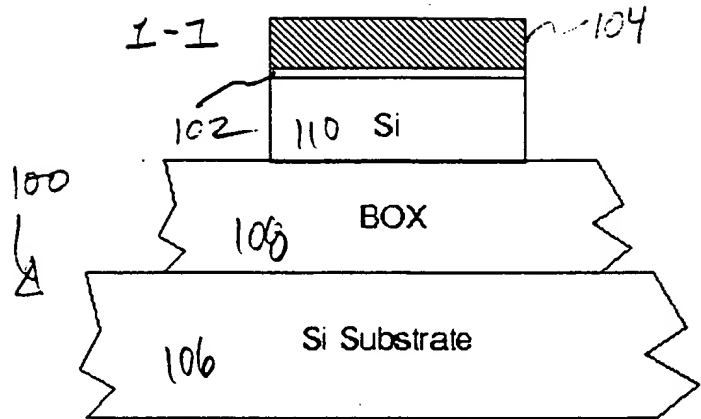


FIG 13

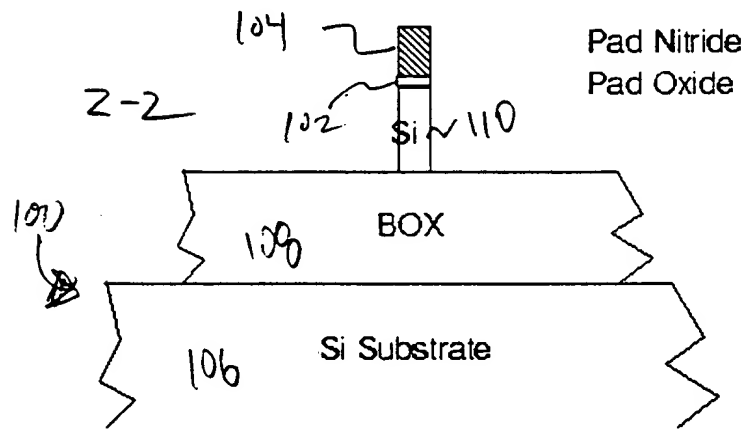


Fig 1C

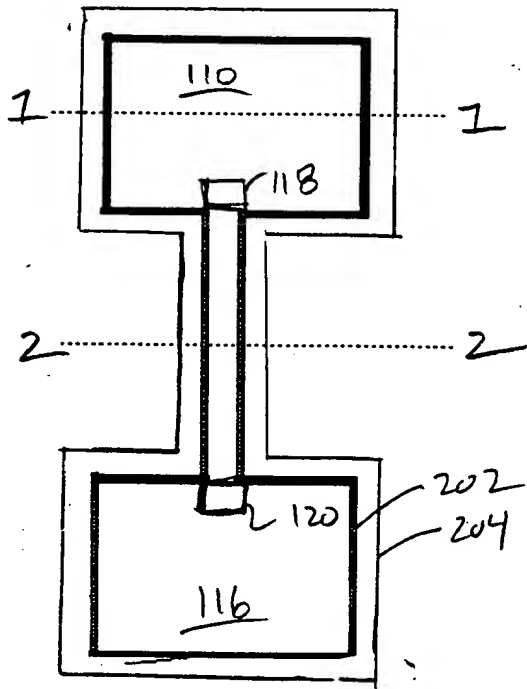


FIG 2A

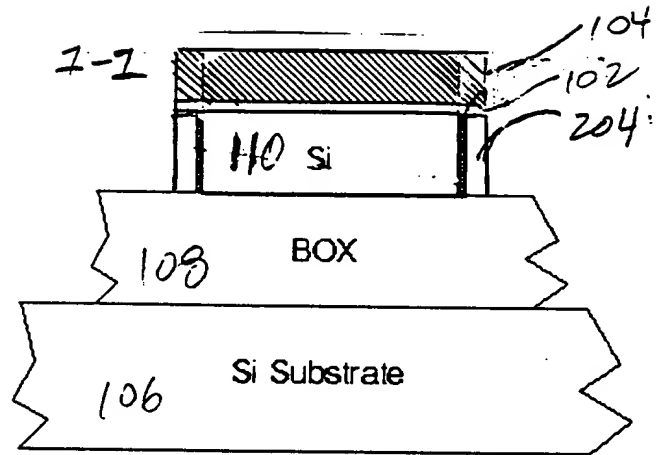


FIG 2B

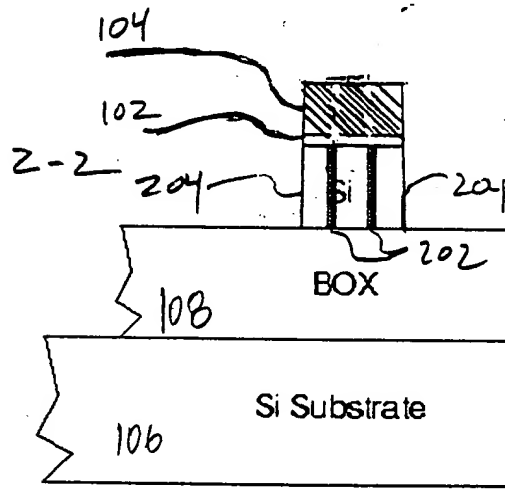


FIG 2C

FIG. 2

000001-000000

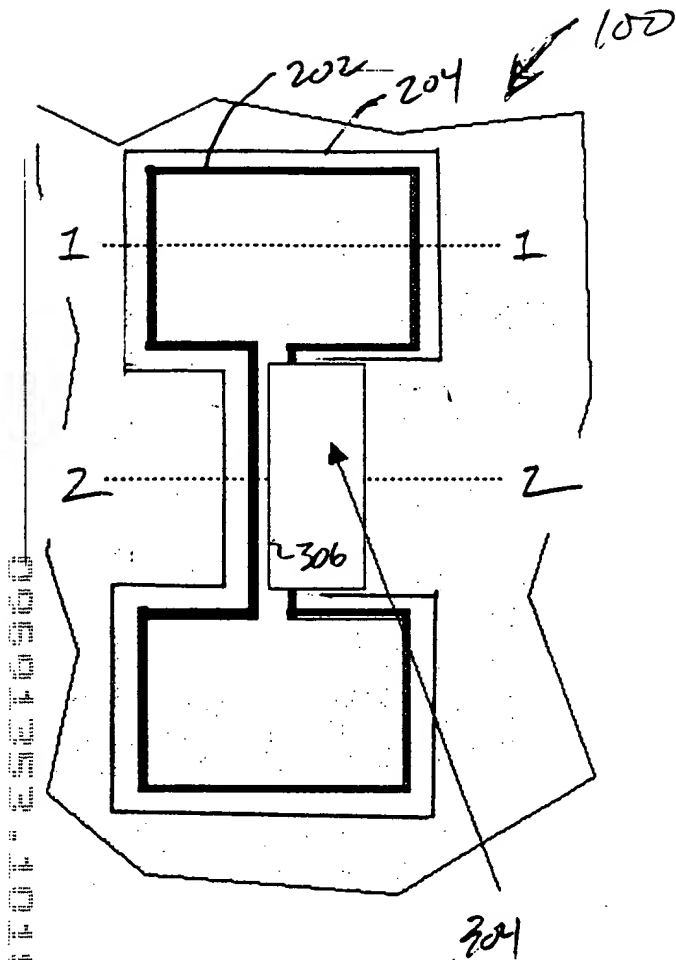


FIG 3A

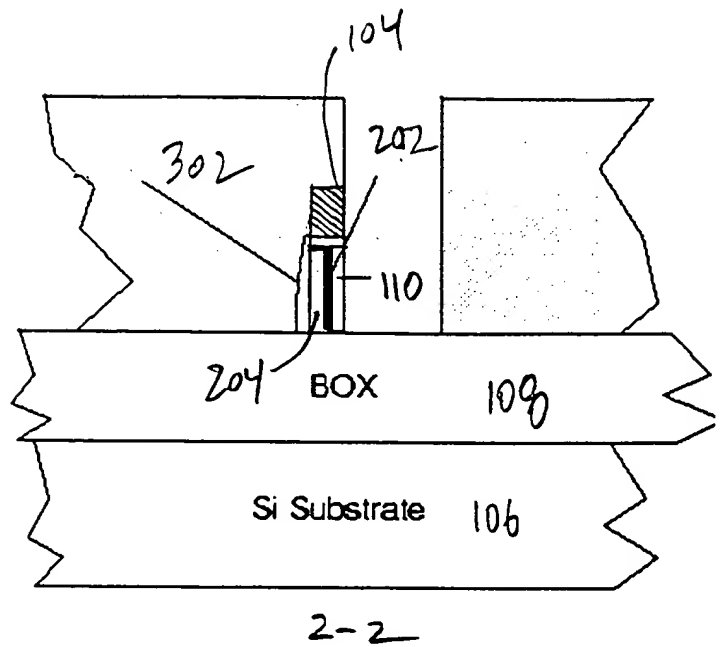


FIG 3B

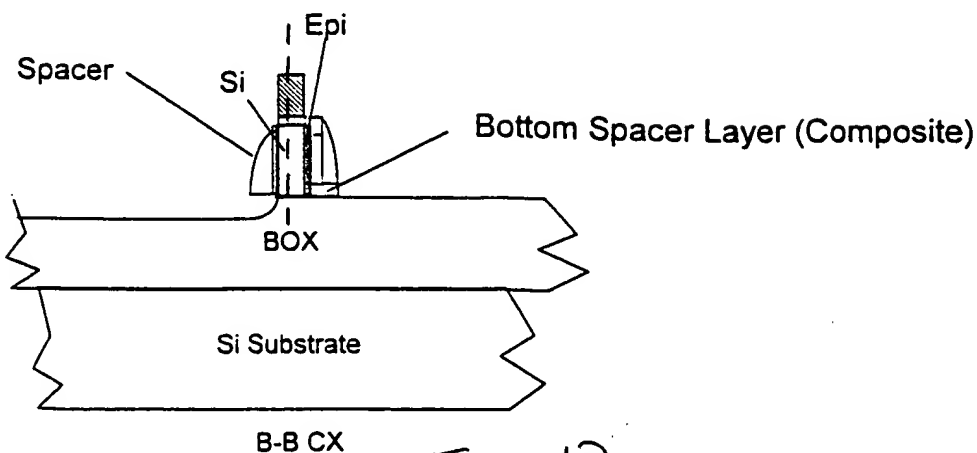


FIG. 12

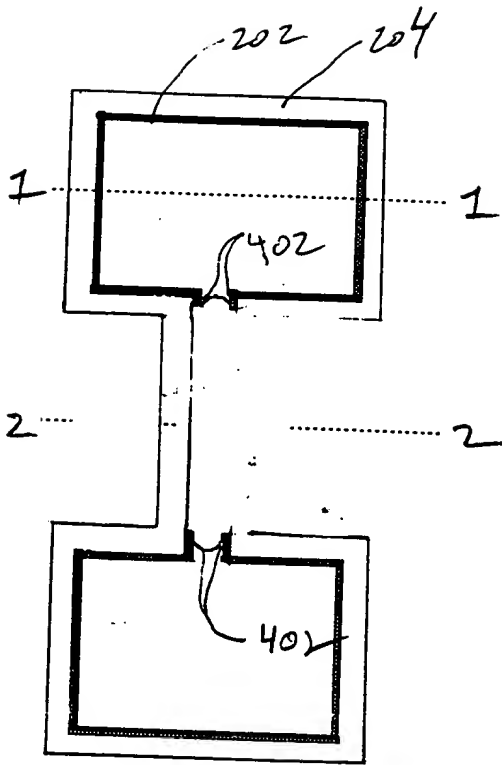


FIG 4A

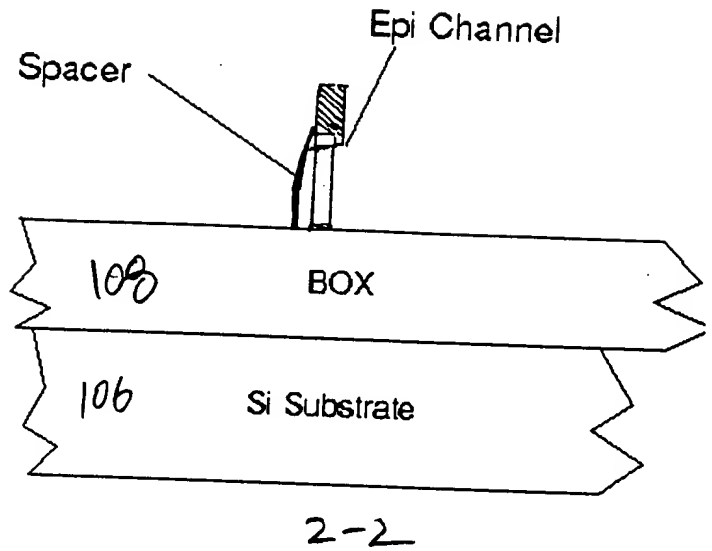


FIG 4B

FIG. 4

5/10

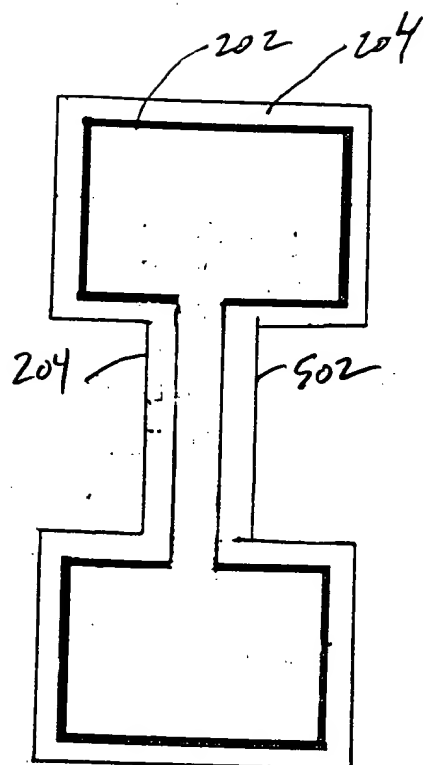


FIG 5



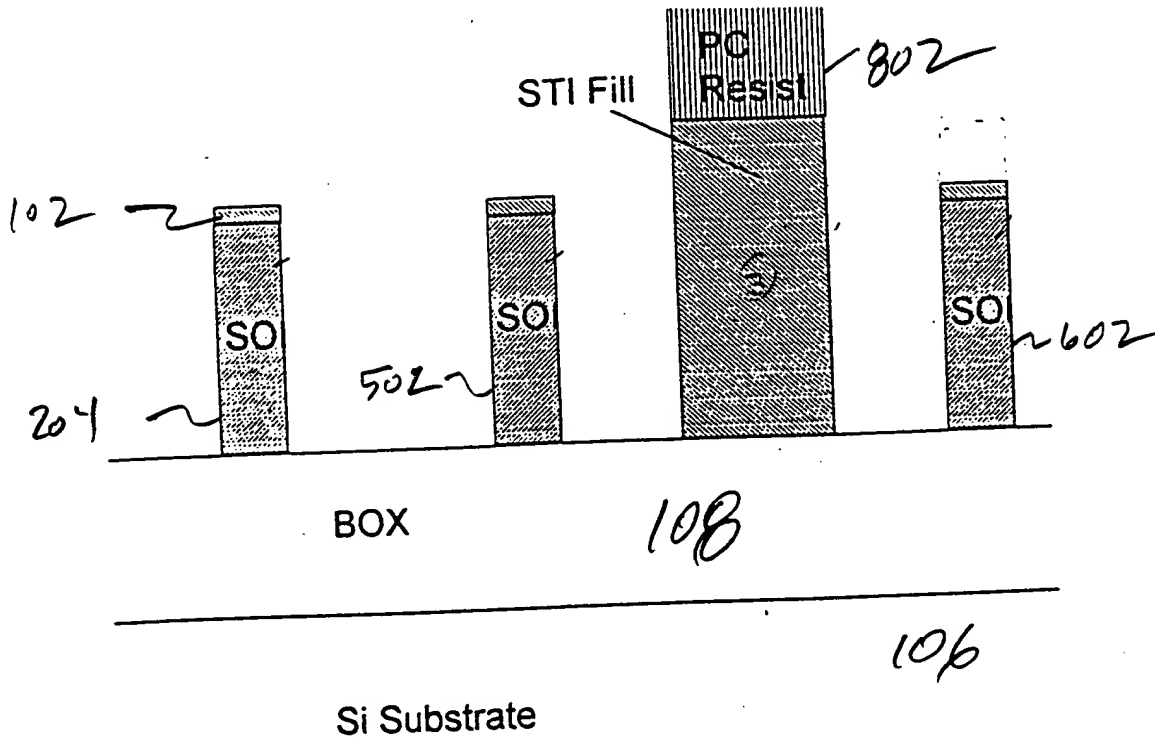


Fig 8A

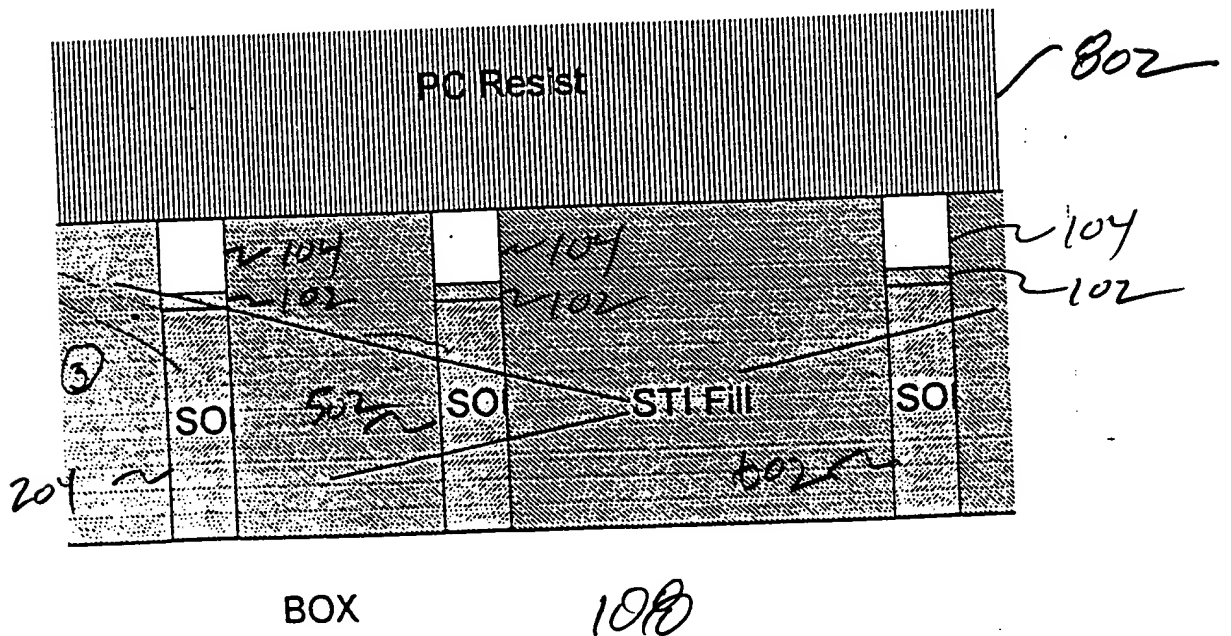
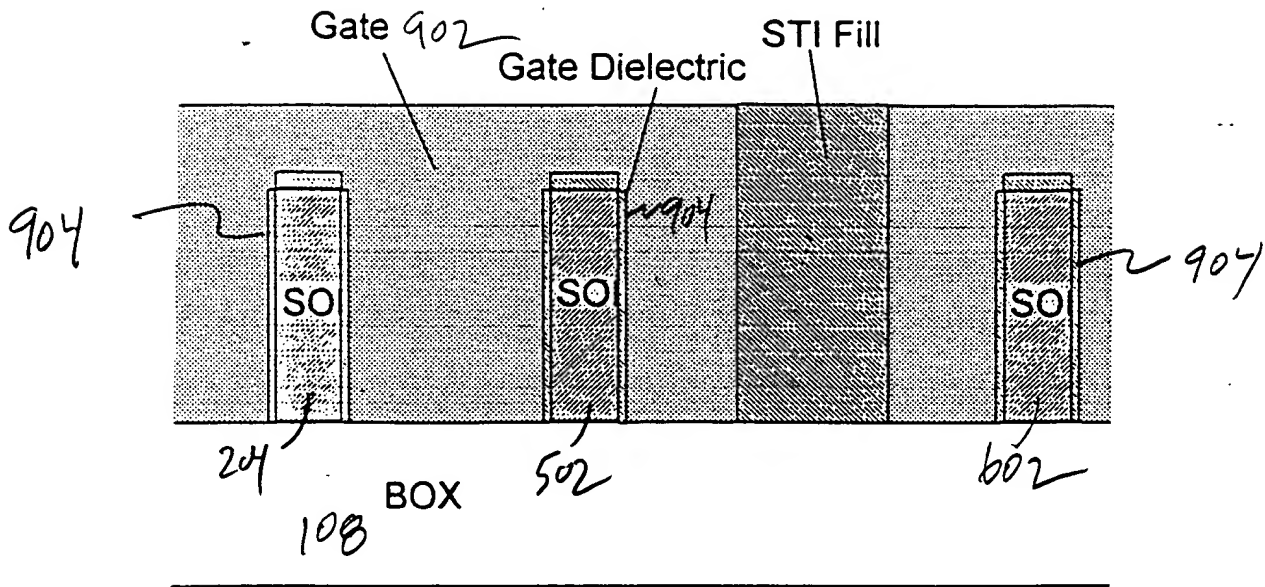


Fig 8B



Si Substrate

Fig. 9A

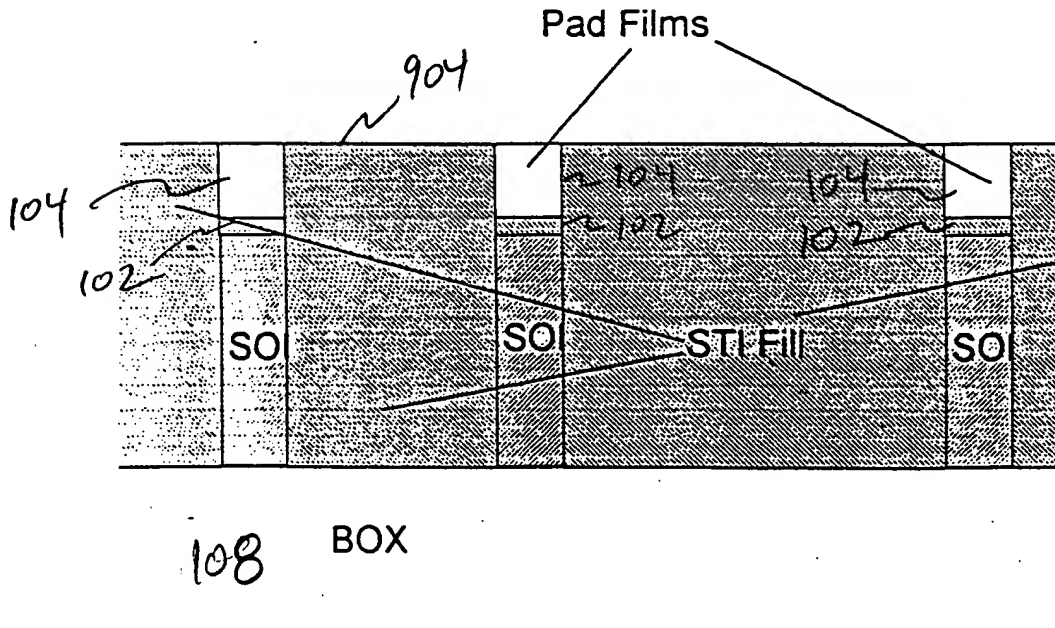


Fig. 9B



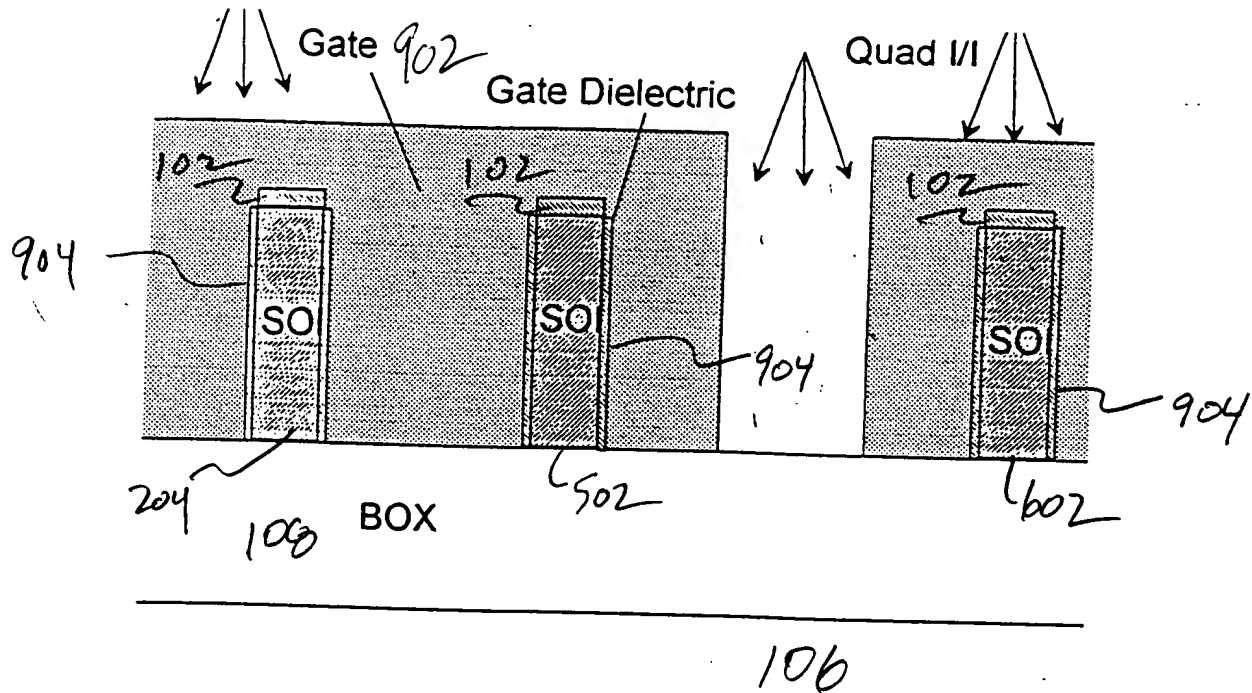


Fig 10A

Extension Implant - Done w/ angle relative to substrate and repeated 4 times at cardinal directions relative to notch.

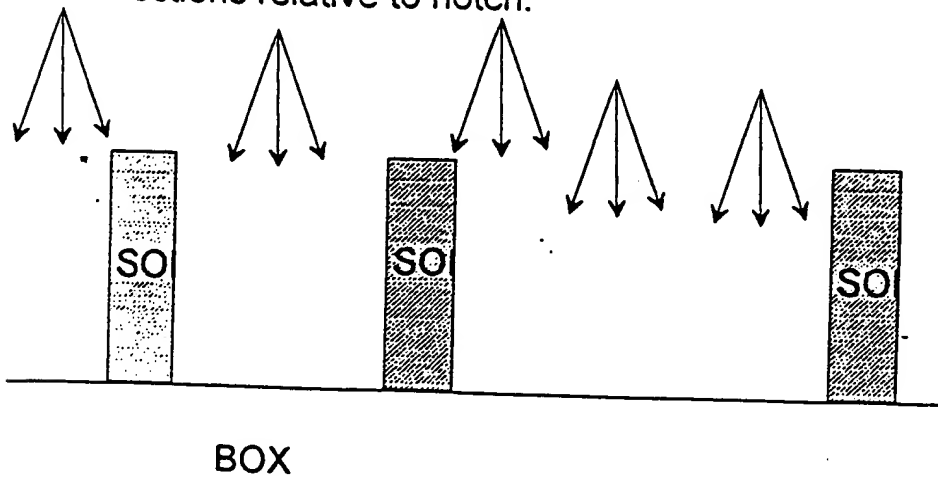


Fig 10B

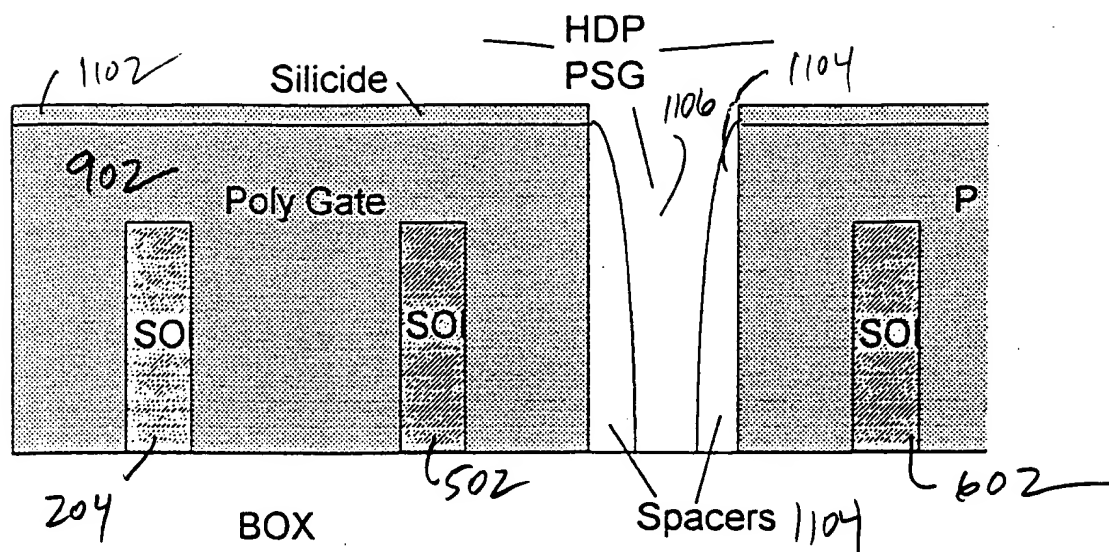


Fig 11A

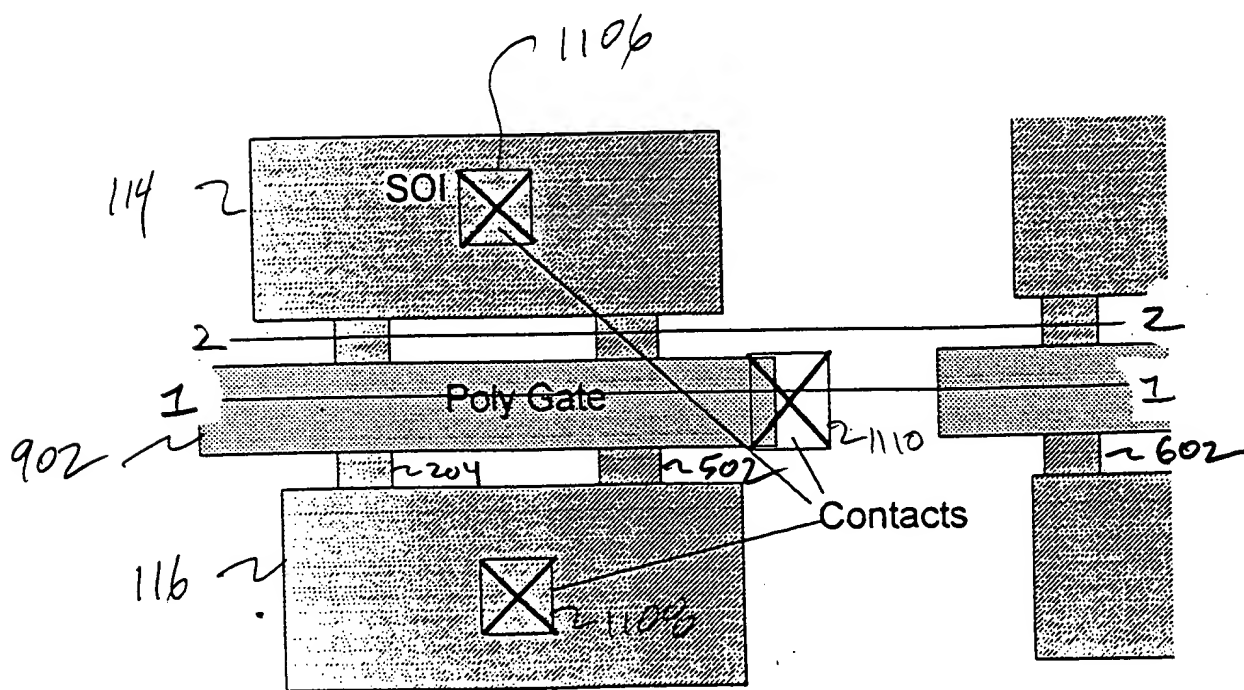


Fig 11B